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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/715,248	11/17/2003	Nathan R. Brown	2269-4375.2US (99-1029.02	4988
24247 7	590 05/12/2004		EXAMINER	
TRASK BRITT P.O. BOX 2550			THOMAS,	DAVID B
	OTTY, UT 84110	•	ART UNIT	PAPER NUMBER
	, 01 0		3723	

DATE MAILED: 05/12/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application	n No.	Applicant(s)			
		10/715,24	8	BROWN, NATHAN R.			
	Office Action Summary	Examiner		Art Unit	-		
		David B. T		3723			
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply							
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication. - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).							
Status							
1)🖂	Responsive to communication(s) filed on 1	7 November 20	<u>003</u> .				
•	This action is FINAL . 2b) This action is non-final.						
3)□	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.						
Dispositi	ion of Claims						
4) Claim(s) 1-21 is/are pending in the application. 4a) Of the above claim(s) is/are withdrawn from consideration. 5) Claim(s) is/are allowed. 6) Claim(s) 1,6,12 and 18-21 is/are rejected. 7) Claim(s) 1-21 is/are objected to. 8) Claim(s) are subject to restriction and/or election requirement.							
Applicati	ion Papers						
9) The specification is objected to by the Examiner. 10) The drawing(s) filed on 17 November 2003 is/are: a) accepted or b) objected to by the Examiner. Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a). Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d). 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.							
Priority (ınder 35 U.S.C. § 119						
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 							
2) Notice 3) Information	et (s) te of References Cited (PTO-892) te of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB tr No(s)/Mail Date 11/17/03.		4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:				

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DETAILED ACTION

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1, 6, 12, and 18-21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Leach (5,607,341).

Leach ('341) discloses a system for polishing a semiconductor device, the system having a support structure, a plurality of independently movable pressurization structures, and an actuator corresponding to each of the plurality of pressurization structures has an annular shape, the actuator has a positive pressure source, and a polishing component which comprises both a mechanical and a chemical mechanical polishing apparatus, a rotatable polishing pad, and an element for rotating the semiconductor device structure in a plane. Leach ('341) also discloses that it was known in the art to apply metrology in the art of CMP (see the prior art reference to Howland et al., "Metrology and Inspection Techniques for CMP Applications", Semicon West, pp. 1-27, 1994.) Hence, Leach ('341) discloses the claimed invention except for using one magnet to actuate the plurality of independently movable pressurization structures, via a magnetic fluid, rather than a plurality of actuators, or for positively applying metrology techniques to detect any raised areas on the surface of the semiconductor. Therefore, it would have been

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obvious to one having ordinary skill in the art at the time the invention was made to have modified the system of Leach ('341) by providing a metrology component to detect any raised areas on the semiconductor, as Leach ('341) has disclosed that such was known in the art, and further providing a plurality of actuators for enhancing the control of the force applied to the plurality of independently movable pressurization structures, in order to maximize the planarity of the semiconductor device during the polishing process.

Double Patenting

- 3. Claims 1-21 of this application conflict with claims 62-82 of Application No. 09/912,982. 37 CFR 1.78(b) provides that when two or more applications filed by the same applicant contain conflicting claims, elimination of such claims from all but one application may be required in the absence of good and sufficient reason for their retention during pendency in more than one application. Applicant is required to either cancel the conflicting claims from all but one application or maintain a clear line of demarcation between the applications. See MPEP § 822.
- 4. A rejection based on double patenting of the "same invention" type finds its support in the language of 35 U.S.C. 101 which states, "whoever invents or discovers any new and useful process ... may obtain <u>a</u> patent therefore..." (Emphasis added). Thus, the term "same invention," in this context, means an invention drawn to identical subject matter. See *Miller v. Eagle Mfg. Co.*, 151 U.S. 186 (1894); *In re Ockert*, 245 F.2d 467, 114 USPQ 330 (CCPA 1957); and *In re Vogel*, 422 F.2d 438, 164 USPQ 619 (CCPA 1970).

A statutory type (35 U.S.C. 101) double patenting rejection can be overcome by canceling or amending the conflicting claims so they are no longer coextensive in scope. The filing of a terminal disclaimer <u>cannot</u> overcome a double patenting rejection based upon 35 U.S.C. 101.

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5. Claims 1-21 are objected to under 37 CFR 1.75 as being a duplicate of claims 62-82. When two claims in an application are duplicates or else are so close in content that they both cover the same thing, despite a slight difference in wording, it is proper after allowing one claim to object to the other as being a substantial duplicate of the allowed claim. See MPEP § 706.03(k).

Conclusion

6. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Chen, Fruitman et al., Kajiwara et al., Kimura et al., Korovin et al., and Leach each disclose a semiconductor polishing system having independently controlled pressurization structures. Hiyama et al., and Molnar each disclose a polishing apparatus, which utilizes magnetic force.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to David B. Thomas whose telephone number is (703) 308-4250. The examiner can normally be reached on 7-4 M-F.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Joseph J. Hail can be reached on (703) 308-2687. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only.

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For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

David B. Thomas Patent Examiner Art Unit 3723

dbt